

Reducing RF-power and x-ray load in ECRIS by metal-dielectric (MD) structures

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Metal dielectric structures (MD) installed in the plasma chamber of the Frankfurt 14 GHz ECRIS, have been used to significantly reduce the level of microwave power, necessary to extract ion intensities comparable to those extracted from the standard ECRIS (all stainless steel).

The measurements indicate that the RF power may be reduced by factors of 2-3, to obtain the same output of high argon charge states as in the standard source. This reduced level of microwave power also leads to a much lower load of Bremsstrahlung radiation from the source.





MD in the plasma chamber:

- Increase of electron-density and temperature
- Operation at lower pressure
- Operation with reduced RF-power
 - Increase of the HCS ion production
 - Imiting plasma instabilities
 - minimize charge exchange processes and recombinations
 - RF power saving by a factor 2-3
 - reduced X-rays emission

Saving RF-power by MD:



IF you don't like x-ray emission!



X-ray emission is reduced by a factor 10 for the source equipped with MD structures as compared to the " standard" (all stainless steele) source. (The source has been optimized for the extraction of Ar-12⁺ ions)

X-ray spectra at 800 W RF Power for the standard source and the source equipped with MD- structures



The source has been optimized for the extraction of Ar-8⁺ ions



MD versus gas-mixing



MD liner+ MD exraction electrode inserted in the plasma chamber :

- → Much stronger effect with MD
- extracted currents of Ar-14⁺ ions are increased by a factor of 7 compared to the standard mode of operation.
- Set y gas mixing in the presence of MD increased the performance by another factor of ≤ 2
- negligible content of support gases
 (e.g. O₂)



MD versus gas-mixing INTRISIC EFFECTS



MD liner inserted in the plasma chamber L. Schachter, et al.; Rev. Sci. Instr. 71,Vol. 2, p.918,(2000)

$$I_{(MD, Ar)} / I_{(st.st. Ar+O^2)} = 3.3$$

for Ar¹⁶⁺

MD intrisic effect is 3 times stronger than the gas mixing effect for very high charge states

CONCLUSION



 Significantly stronger production of high charge state ions

•Saves RF power

Significant lower X-rays emission

•Reduced ECRIS design restrictions